Course Title	()	()) Semiconductor Fabrication Processes
--------------	-----	-----	---------------------------------------

() Lecturer	()	/ / (Course No. /)	006147/ /3	
(/HP) Contact No.			/ (Class Hour/Venue)	13: 30-15: 00 / 109	
(Course Prerequisite)			(Target Student)	4	
E-mail (E-mail Address)			/Office Hour (Office/Office Hour)	812 / 15: 00-17: 00	

(Objectives)	. (crystal growth, cleaning, lithography, oxidation, diffusion, ion implantation, thin film deposition, etching, back-end processing) , , . Term Project
CQI (Continuous Quality Improvement Plan)	- update: 1 - Flipped learning :
(Text book & References)	- Plummer et al., "Silicon VLSI Technology: Fundamentals, Practice, and Modeling", Prentice Hall (2000) - Xiao, "Introduction to Semiconductor Manufacturing Technology", Prentice Hall (2001) - , (2014)
(Assignment book)	- "Silicon Run" VTR tape () - Doering and Nishi(ed), "Handbook of Semiconductor Manufacturing Technology" (2007)
(Lecture Methods)	- LCD projector
(Assignment)	- " " " - " O
(Reading Materials)	- chapter
가 (Course Grading)	[フト] (%): 30, (%): 40, フト (%): 20, (%): 10, - : 4/23(), : 6/18() - F .
(Etc.)	- 가 가 . -

(:)

(Week)	(Course Contents)	(Etc.)	
1	Introduction and Historical Perspective		
2	Modern CMOS Technology		
3	CMOS Process Flow		
4	Fabrication and Basic Properties of Silicon Wafers		
5	Clean Rooms, Wafer Cleaning, and Gettering		
6	Li thography		
7	Thermal Oxidation and the Si/SiO2 Interface		
8			

(:)

(Week)	(Course Contents)	(Etc.)	
9	Dopant Diffusion		
10	Ion Implantation		
11	Thin Film Deposition I		
12	Thin Film Deposition II		
13	Etchi ng		
14	Team Project Presentation		
15	Interconnect		
16			

